

PTO-1449 Information Disclosure Citation in an Application	Application No. TBD 09/1732468	Applicant(s) Christopher M. Bowles, et al.
	Docket Number TI-24521	Group Art Unit TBD
		Filing Date 12/07/00

U.S. PATENT DOCUMENTS

	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
A	5,536,675	07/16/96	Bohr	437	67	08/07/95
B						
C						
D						
E						
F						
G						
H						
I						
J						
K						
L						
M						

FOREIGN PATENT DOCUMENTS

	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
N							
O							
P							
Q							
R							

NON-PATENT DOCUMENTS

	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
S	'A New Planarization Technique, using a Combination of RIE and Chemical Mechanical Polish (CMP) by B. Davari, et al.; IEEE © 1989, pp. 3.4.1 - 3.4.4	1989
T		
U		

EXAMINER <i>Messy Li-han</i>	DATE CONSIDERED 12/21/01
---------------------------------	-----------------------------

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.